# Special Issue

# Micro and Nano Technology in Gas Sensing

## Message from the Guest Editors

The Special Issue "Micro and Nano Technology in Gas Sensing" aims to present the latest topical research in the field of the development of promising gas-sensitive nanomaterials, selection of a method for measuring and processing of a sensor signal, as well as improving the design of sensors, miniaturization of their components, and optimization of energy consumption. All types of submissions are welcome.

- The synthesis and characterization of gas sensing materials based on nanocrystalline metal oxides, composites, perovskites, sulfides, graphene-based materials, quantum dots, surface modification, and functionalization.
- Evaluation of surface reactivity of gas sensing materials, adsorption and desorption of gases, investigations of gas-sensing mechanisms.
- Semiconductor gas sensing materials for gas detection under UV or visible photoactivation, the use of photoactivation to reduce the energy consumption of sensors.
- Approaches to the miniaturization and integration of gas sensors, reducing the size of sensitive, heating, or light-emitting elements.
- Manufacturing of sensors on flexible or transparent substrates, printed and patterned gas sensors.

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## Deadline for manuscript submissions

closed (25 December 2023)

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# About the Journal

## Message from the Editor-in-Chief

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## Editor-in-Chief

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